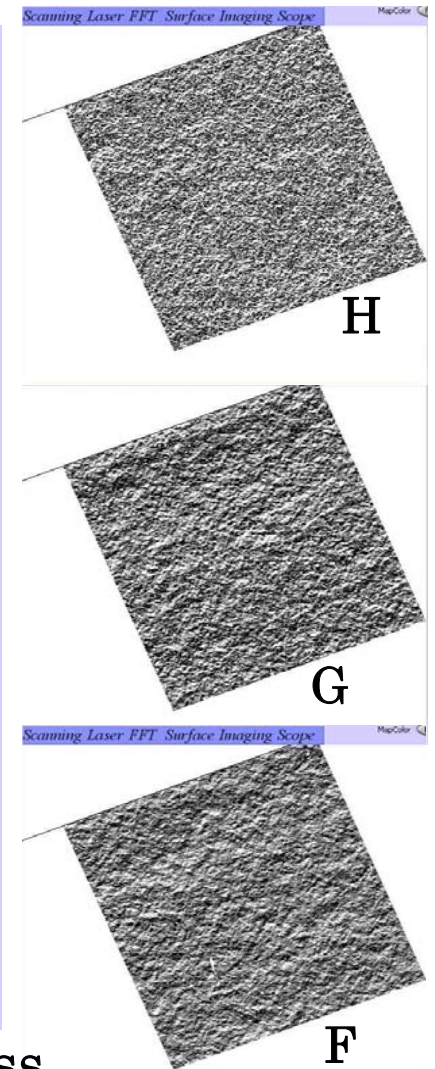
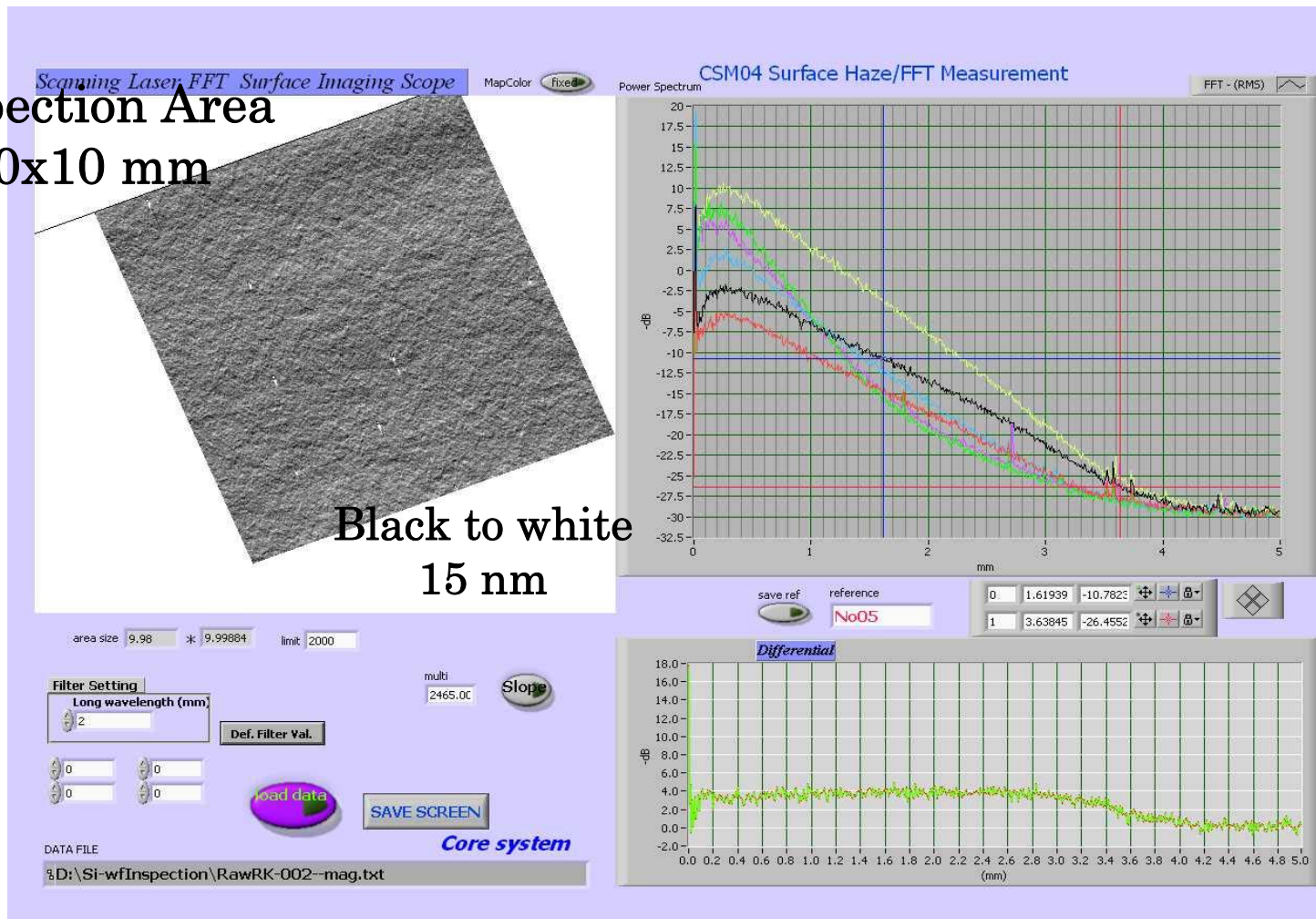
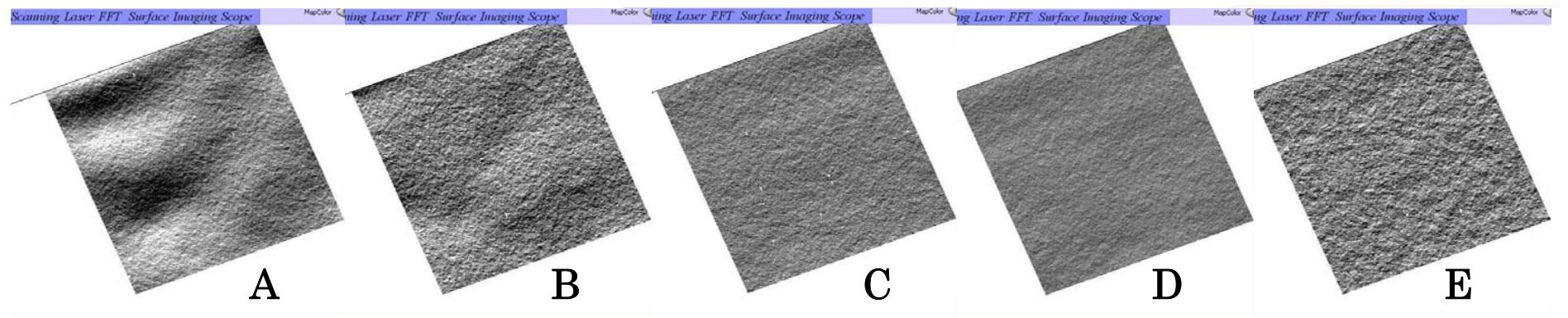


Inspection Area
10x10 mm

Black to white
15 nm



Si wafer surface inspection FFT analyze-comparison process



auto home
OK

exchange
OK

stage speed OFF
optical setting OFF
manual view OFF
caution OFF

Inspection

inspection Err
Filter too big
Y+ small
Y- small

X axis(mm) readX X- 15 X+
Y axis(mm) readY Y- 15 Y+
manual (theta(deg) Ystep Frequency
OFF 0 0.02 1M Hz

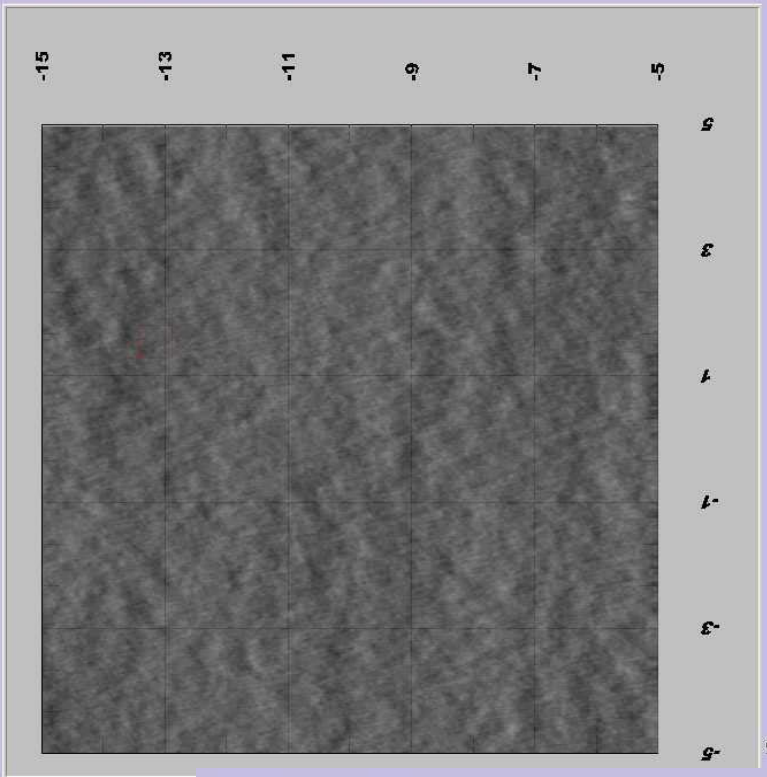
Y-axis Line Position

X-axis Profile 1.540

Cursor0 -6.81922 -1.06502
Cursor1 -6.24727 0.51526

X-axis Line Position Max HeightY 1.64 X 2.13
Y-axis Profile -13.2 MinHeightY -1.91 X -1.97

CSM04 Imaging Scope By Core System



View
measure
inspect
repaint

save OFF
load OFF
old data OFF

autohome
manual
exchange
stop
xy projection OFF
String need interlock

Read POS
Span 50.00
Filter
Lower Cut-Off 1200
Custom Colors

relo

integral
normal

CSM04 Imaging Scope By Core System

DATA FILE
D:\Coresystem\RawNGS10-mag.txt

CSM04 Imaging Scope By Core System

DATA FILE
D:\Coresystem\RawRL-002-mag.txt

exchange
OK

stage speed OFF
optical setting OFF
manual view OFF
caution OFF

Inspection

inspection Err
Filter too big
Y+ small
Y- small

X axis(mm) readX X- 15 X+
Y axis(mm) readY Y- 15 Y+
manual (theta(deg) Ystep Frequency
OFF 0 0.02 1M Hz

Y-axis Line Position

X-axis Profile 1.540

Cursor0 -6.81922 -1.06502
Cursor1 -6.24727 0.51526

X-axis Line Position Max HeightY 1.64 X 2.13
Y-axis Profile -13.2 MinHeightY -1.91 X -1.97

DATA FILE
D:\Coresystem\Wo01-30-30-60

CSM04 Imaging Scope By Core System

DATA FILE
D:\Coresystem\RawRK-002-mag.txt

Black to white
15 nm
Inspection Area
30x30 mm
Si wafer surface analyze
comparison process